

Fig. 1 Etch rates and saturation curves of single-crystalline (a) AIN and (b) GaN

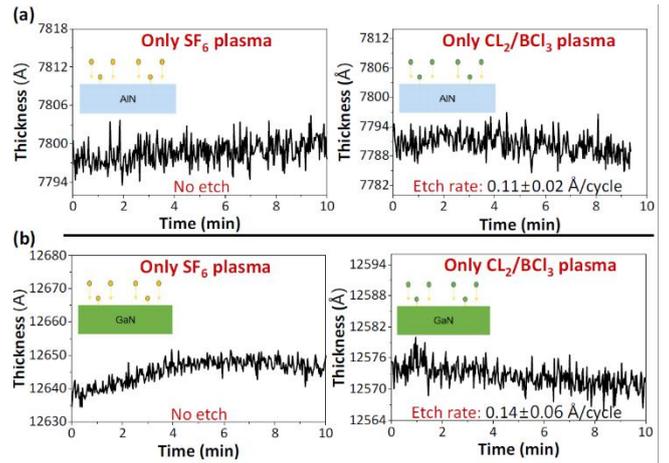


Fig. 2 Isolated half-reactions for (a) AIN and (b) GaN

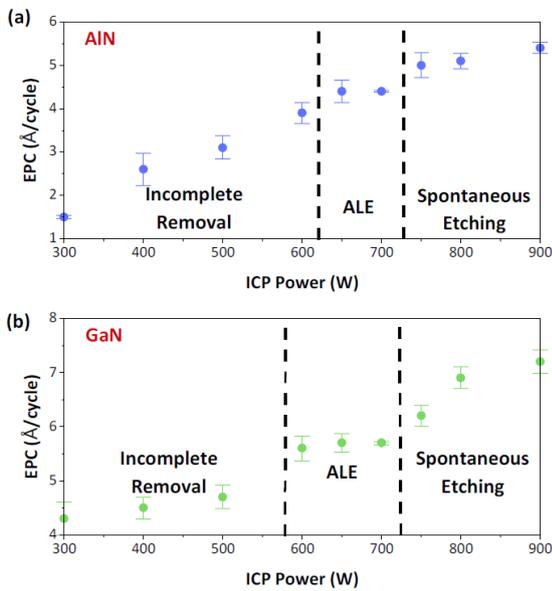


Fig. 3 Effect of ICP power on the EPC of (a) AIN and (b) GaN

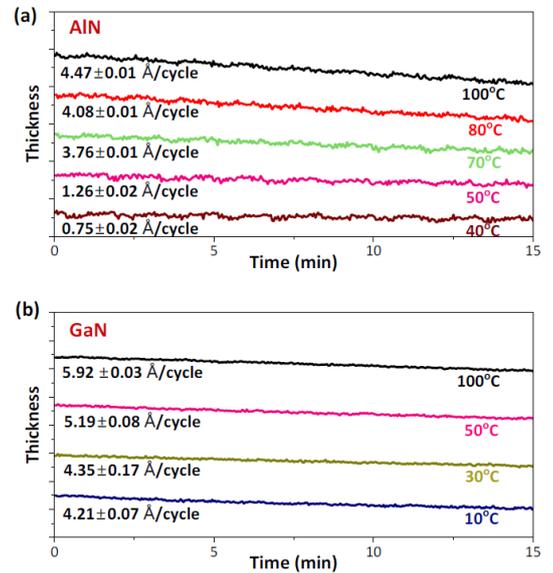


Fig. 4 Temperature dependence of EPC of (a) AIN and (b) GaN

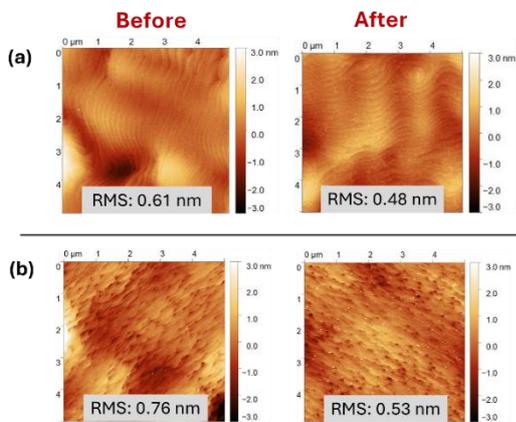


Fig. 5 $5 \times 5 \mu\text{m}^2$ AFM scans before and after 30 cycles of ALE of (a) AIN and (b) GaN

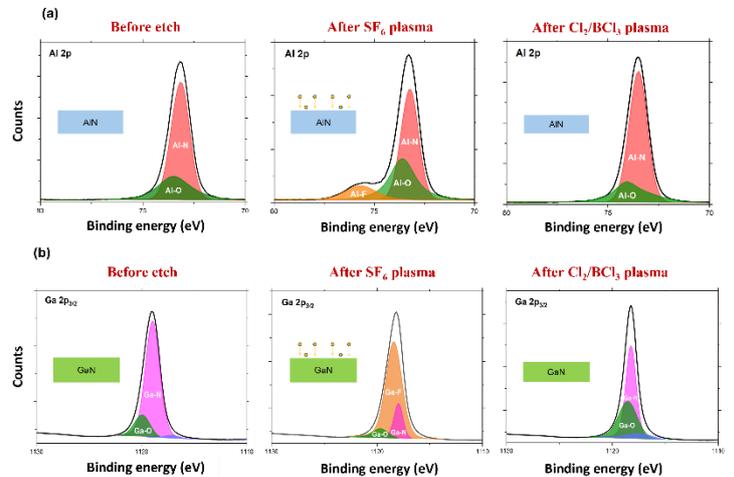


Fig. 6 XPS analysis of etch mechanism